

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 10/671,922  
Filing Date ..... September 24, 2003  
Inventor ..... Garo J. Derderian et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2812  
Examiner ..... Ahmadi, Mohsen  
Attorney's Docket No. .... MI22-2296  
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over  
Semiconductor Substrates

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

The attached Form PTO/SB/08a is submitted in compliance with 37 C.F.R. §§ 1.56. Pursuant to Federal Register Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. Copies of all other cited art references, if any, are attached. No admission is made regarding whether all the submitted references are prior art. Citation of these references is respectfully requested.

Respectfully submitted,

Dated: June 29, 2007

By: Jennifer J. Taylor

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